PATENT ASSIGNMENT

Electronic Version v1.1
Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
REPLISAURUS TECHNOLOGIES AB	11/04/2010
REPLISAURUS TECHNOLOGIES INC	11/04/2010

RECEIVING PARTY DATA

Name:	REPLISAURUS GROUP SAS
Street Address:	Le Soleil Levant, Immeuble Sendai 11, chemin des Anciennes Vignes
City:	69410 Champagne au Mont d'Or
State/Country:	FRANCE

PROPERTY NUMBERS Total: 11

Property Type	Number
Application Number:	61364989
Application Number:	12085176
Application Number:	12085157
Application Number:	12094142
Application Number:	12412319
Application Number:	12470448
Application Number:	12801219
Application Number:	12412322
Application Number:	12470452
Application Number:	12470444
Patent Number:	7790009

OP $440.00 61364989

CORRESPONDENCE DATA

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ATTORNEY DOCKET NUMBER:	10760.0001, 02, 03, 04,60
NAME OF SUBMITTER:	Veronica Bayne

Total Attachments: 5
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source=Assignment_Recordation#page5.tif

RECORDATION FORM COVER SHEET **PATENTS ONLY**	**U.S. Department of Commerce** **Patent and Trademark Office** **Attorney Docket No. 10760.0001, 0002, 0003, 0004, and 6000**
To the Director of the U.S. Patent and Trademark Office: **Please record the attached original documents or copy thereof.**	**Mail Stop Assignment Recordation Services**

1. Name of conveying party(ies): **a) REPLISAURUS TECHNOLOGIES AB** **b) REPLISAURUS TECHNOLOGIES INC**	2. Name and address of receiving party(ies): Name: **REPLISAURUS GROUP SAS**
Additional name(s) of conveying party(ies) attached? ☐ Yes ☒ No	Internal Address:
3. Nature of conveyance:	Street Address: **Le Soleil Levant, Immeuble Sendaï** **11, chemin des** **Anciennes Vignes**
☒ Assignment ☐ Merger	City: **69410 Champagne au Mont d'Or, FRANCE**
☐ Security Agreement ☐ Change of Name	State: Zip Code:
☐ Joint Research Agreement ☐ Government Interest Assignment	Additional name(s) & Address(es) attached? ☐ Yes ☒ No
☐ Executive Order 9494, Confirmatory License ☐ Other:	
Execution Date: **November 4, 2010**	

4. Application number(s) or patent number(s): If this document is being filed together with a new application, the execution date of the application:

A. Patent Application Number(s): **61/364,989; 12/085,176; 12/085,157; 12/094,142; 12/412,319; 12/470,448; 12/801,219; 12/412,322; 12/470,452; AND 12/470,444**	B. Patent Number(s): **7,790,009**

Additional numbers attached? ☐ Yes ☒ No

5. Name and address of party to whom correspondence concerning document should be mailed:	6. Total number of applications and patents involved: 10 (Ten)
Name: **Gerson S. Panitch** **(202) 408-4000**	7. Total fee (37 CFR 1.21(h) and 3.41): **$40 X 11 = $440**
Internal Address: **FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER, L.L.P.**	☒ Enclosed (Please charge deficiency or credit overpayment to deposit account 06-0916)
Street Address: **901 New York Avenue, N.W.**	
City: **Washington, D.C.**	☐ Authorized to be charged to deposit account
State: Zip: **20001-4413**	8. Deposit Account No.: **06-0916**

9. Statement and signature.

To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Signed: ______________________ **December 10, 2010**

James D. Stein Date
Reg. No. 63,782

Total number of pages including cover sheet, attachments and documents: -5-

6/2007

ASSIGNMENT

On this day, the 4th of November 2010,

it is hereby declared that we have assigned to:

REPLISAURUS GROUP SAS
Le Soleil Levant, Immeuble Sendaï 11, chemin des
Anciennes Vignes
69410 Champagne au Mont d'Or,
France

Our entire rights in and to all patent applications and patents - as per enclosure 1 - now registered with

REPLISAURUS TECHNOLOGIES AB
Isafjordsgatan 22 B, 5v
SE-164 40 KISTA
Sweden

and

REPLISAURUS TECHNOLOGIES INC
1209 Orange Street
WILMINGTON, DE 19801
USA

as applicants.

4- 11- 2010
Place and date

REPLISAURUS TECHNOLOGIES AB

Signature of Assignor

DANIEL A. CARL
Name in block letters

4-11-2010

REPLISAURUS TECHNOLOGIES INC

Signature of Assignor

DANIEL A. CARL
Name in block letters

The above assignment is accepted.

REPLISAURUS GROUP SAS

Place and date: 4/11/2010

Signature of Assignee

[illegible]
Name in block letters

It is hereby certified that th[illegible]
true and correct copy of th[illegible]
document: Anita Rydberg

ENCLOSURE 1

Patent applications as per November 4, 2010

Ref. no.	State	Application no.	Pat./Reg.nr	Title	Applicant
P52190001	Sweden	0102144-3	523 309	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
E52190001	E P O	02739042.6		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
E52191001	E P O	10182946.3		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001CA	Canada	2,462,098		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001CN	China	02811926.6	ZL02811926.6	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001HK	Hong Kong	05104929.3	HK1072083	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001IN	India	02129/DELNP/2003		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001JP	Japan	2003-505393	4546078	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52191001JP	Japan	2009-142804		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001KR	South Korea	2003-7016336		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001MY	Malaysia	PI 20034732		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001PH	Philippines	1-2003-501274	1-2003-501274	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001RU	Russia	2003136088	2296820	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001SG	Singapore	200307357-4	101 252	METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52190001US	USA	10/734 223		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
P52192001US	USA	12/801 219		METHOD FOR DEFINING AND REPLICATING STRUCTURE IN CONDUCTING MATERIAL	REPLISAURUS TECHNOLOGIES AB
E52190002	E P O	06813033.5		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002CN	China	200680051024.3		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002JP	Japan	2008-541118		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002KR	South Korea	2008-7014730		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52190002US	USA	12/085 176		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52191002US	USA	12/412 319		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB
P52192002US	USA	12/412 322		METHOD OF FORMING A MULTILAYER STRUCTURE	REPLISAURUS TECHNOLOGIES AB

ENCLOSURE 1

Patent applications as per November 4, 2010

E52190003	E P O	06824464.9	ELECTRODE AND METHOD OF FORMING THE ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52190003CN	China	200680051145.8	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52190003JP	Japan	2008-541119	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52190003KR	Sydkorea	2008-7014733	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52190003US	USA	12/085 157	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52191003US	USA	12/470 448	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52192003US	USA	12/470 452	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
P52193003US	USA	12/470 444	MASTER ELECTRODE AND METHOD OF FORMING THE MASTER ELECTRODE	REPLISAURUS TECHNOLOGIES AB
E52190005	E P O	06813034.3	MASTER ELECTRODE AND METHOD OF FORMING IT	REPLISAURUS TECHNOLOGIES AB
P52190005CN	China	200680051055.9	MASTER ELECTRODE AND METHOD OF FORMING IT	REPLISAURUS TECHNOLOGIES AB
P52190005JP	Japan	2008-541120	MASTER ELECTRODE AND METHOD OF FORMING IT	REPLISAURUS TECHNOLOGIES AB
P52190005KR	South Korea	2008-7014735	MASTER ELECTRODE AND METHOD OF FORMING IT	REPLISAURUS TECHNOLOGIES AB
P52190005US	USA	12/094 142	MASTER ELECTRODE AND METHOD OF FORMING IT	REPLISAURUS TECHNOLOGIES AB
W52190006	P C T	PCT/EP2008/009658	A SYSTEM FOR PLATING A CONDUCTIVE SUBSTRATE, AND A SUBSTRATE HOLDER FOR HOLDIN	REPLISAURUS TECHNOLOGIES INC
P52190006TW	Taiwan	98131796	A SYSTEM FOR PLATING A CONDUCTIVE SUBSTRATE, AND A SUBSTRATE HOLDER FOR HOLDIN	REPLISAURUS TECHNOLOGIES INC
P52190007	Sweden	1050795-2	SYSTEM FOR AUTOMATED HANDLING OF MASTERS AND SUBSTRATE	REPLISAURUS TECHNOLOGIES AB
P52190007US	USA	61/364 989	NEW MATTER	REPLISAURUS TECHNOLOGIES AB
P52190008	Sweden	1050796-0	A CHUCK, AND A METHOD FOR BRINGING A FIRST AND A SECOND SUBSTRATE TOGETHER	REPLISAURUS TECHNOLOGIES AB
P52190009	Sweden	1050797-8	CONTACT BRINGING MEANS FOR AN ECPR MASTER ELECTRODE AND A SUBSTRATE TOGETHE	REPLISAURUS TECHNOLOGIES AB
P52190010	Sweden	1050798-6	SEPARATION OF MASTER ELECTRODE AND SUBSTRATE IN ECPR	REPLISAURUS TECHNOLOGIES AB
P52190011	Sweden	1050799-4	LEVELING OF MASTERELECTRODE AND SUBSTRATE IN ECPR, AND A CHUCK THEREFORE	REPLISAURUS TECHNOLOGIES AB

ENCLOSURE 1

Patent applications as per November 4, 2010

P52190012	Sweden	1050800-0	FILLING OF A PRINTING CHAMBER AND A CHUCK THEREFORE	REPLISAURUS TECHNOLOGIES AB
P52190013	Sweden	1050801-8	RINSING/DRYING - METHOD FOR RINSING AND/OR DRYING AN ECPR CHAMBER, AND CHUCKS	REPLISAURUS TECHNOLOGIES AB
P52190014	Sweden	1050802-6	DEVICE, SYSTEM AND METHOD FOR USE IN MACHINES FOR ELECTROCHEMICAL PATTERN REP	REPLISAURUS TECHNOLOGIES AB
P52190015	Sweden	1050803-4	METHOD AND SYSTEM FOR DETECTING, SETTING AND MONITORING THE SPATIAL SITUATION	REPLISAURUS TECHNOLOGIES AB

It is hereby certified that this is a
true and correct copy of the original
document: